#### Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

## Listing of Claims:

- (Currently amended) An ion trap, comprising: a three-dimensional rotationally symmetric ring electrode and two cap electrodes with surfaces facing toward the inside of the ion trap, each said two cap electrodes being further composed of a first cone electrode and a second disk electrode; a first means for generating a time-varying, substantially quadrupole field, a second means for generating an independent dipole field; a third means for generating an independent, electrically variable electrostatic DC higher multipole field.
- 2. (Withdrawn) An ion trap of claim 65, comprising: a rotationally symmetric ring electrode cut, in parallel to its central axis, into an even number, equal or larger than four of equal parts and two cap electrodes with surfaces facing toward the inside of the ion trap, said two cap electrode being further composed of a plurality of component electrodes, the surfaces of said ring electrode and cap electrodes being shaped to reduce nonlinearity; means for electrically operating said even number of equal parts to switch said ion trap operation between a three-dimensional mode and a two-dimensional mode; means for generating a time-varying, substantially quadrupole field, said means further compensating the nonlinearity induced quadrupole field distortion when said ion trap operating under the three-dimensional mode; means for generating a linear RF multipole field when said ion trap operating under the two-dimensional mode, wherein said ion trap further includes cutting the three-dimensional rotationally symmetric ring electrode, in parallel to its central axis. Into an even number, equal or larger than four, of equal parts.
- 3. (Previously presented) An ion trap, comprising: a three-dimensional rotationally symmetric ring electrode and two cap electrodes with surfaces facing toward the inside of the ion trap, each said two cap electrodes being further composed of a first cone electrode and a second disk electrode: a RF or periodic circuitry constructed and arranged for applying a RF or periodic voltage to said ring electrode to generate a main quadrupole field in said ion trap; an AC circuitry constructed and arranged for applying an AC voltage to said disk electrodes of said two cap electrodes to generate a dipole field in said ion trap; a DC circuitry constructed and arranged for applying an DC voltage to said cone electrodes of said two cap electrodes to generate an electrically variable electrostatic octopole field in said ion trap

- 4. (Currently amended) An ion trap of claim 1, the cross-section of the surface of each one of the cap electrodes consists of a first portion of spherical surface circle and a second portion of eone surface two straight lines jointed in orthogonal to the circle; the cross-sectional surface of the ring electrode consists of a portion of circle and two straight lines jointed in orthogonal to the circle; the surfaces of the two cap electrodes facing toward the inside of said ion trap.
- 5. (Original) The ion trap of claim 4 wherein said cap electrodes being further divided into a plurality of sets of component electrodes.

## 6. (Cancelled)

- 7. (Previously presented) The ion trap comprising: a three-dimensional rotationally symmetric ring electrode and two cap electrodes with surfaces facing toward the inside of the ion trap, each said two cap electrodes being further composed of a first cone electrode and a second disk electrode: the surface of each one of the cap electrodes consists of first portion of spherical surface and a second portion of cone surface; the cross-sectional surface of the ring electrode consists of a portion of circle and two straight lines jointed in orthogonal to the circle; the surfaces of the two cap electrodes facing toward the inside of said ion trap, said cap electrodes being further divided into a plurality of sets of component electrodes. a RF or periodic circuitry constructed and arranged for applying a RF or periodic voltage to said ring electrode to generate a main quadrupole field in said ion trap; an AC circuitry constructed and arranged for applying an AC voltage to a first set of said plurality of sets of component electrodes to generate a main dipole field in said ion trap; a DC circuitry constructed and arranged for applying an DC voltage to a second set of said plurality of sets of component electrodes to generate an electrically variable electrostatic octopole field in said ion trap.
- 8. (Withdrawn) A two-dimensional ion trap of claim 67, comprising: two trapping plates located in the two terminals of the ion trap device: a set of four predetermined surface-shaped rods located in the center; a set of electrodes located between the set four predetermined surface-shaped rods; a control circuitry for applying a predetermined voltage to said two trapping plates.
- 9. (Withdrawn) The ion trap of claim 8 further comprising a set of short quadrupole rods located between said predetermined surface-shaped rods and said two trapping plates.
- 10. (Withdrawn) The ion trap of claim 8 wherein said a set of electrodes being further composed of a set of four smaller diameter's cylindrical rods
- 11. (Withdrawn) The ion trap of claim 8 wherein said a set of electrodes being further composed of a set of four slice electrodes.
- 12. (Withdrawn) The ion trap of claim 8 further comprising: wherein said first means includes a RF circuitry constructed and arranged for applying a RF voltage to said set of

four predetermined surface snaped rods to generate a main two dimensional quadrupole field; said second means includes an AC offset circuitry constructed and arranged for applying an AC voltage to a pair of said set of four predetermined surface shaped rods to generate a main dipote field; said third means includes a DC circuitry constructed and arranged for applying a DC voltage to said set of electrodes to superimposes a two dimensional electrically variable electrodes octopole field within said two dimensional quadrupole field.

- 13. (Withdrawn) The ion trap of claim 8 wherein said predetermined surface-shaped is quadrupole surface-shaped.
- 14. (Withdrawn) The ion trap of claim 8 wherein said predetermined surface-shaped is cylinder surface-shaped.
- 15. (Withdrawn) A tan lem mass spectrometers, comprising: a collision cell to perform mass fragment, said collision cell having the structure of ion trap as in claim 8.
- 16. (Cancelled)
- 17 (Withdrawn) The ton trap of claim 2 wherein said plurality of even number of component electrodes being equally divided.
- 18. (Withdrawn) The for trap of claim 2 wherein said plurality of even number of component electrodes being unequally divided.
- 19. (Withdrawn) The i in trap of claim 2 wherein said plurality of even number of component electrodes being symmetrically divided.
- 20. (Withdrawn) The im trap of claim 2 wherein said plurality of even number of component electrodes being non-symmetrically divided.
- 21. (Withdrawn) The contrap of claim 17 wherein said even number is chosen from the group of four, six and fight.
- 22. (Withdrawn) The contrap of claim 2 wherein said mechanism constructed and arranged to apply a RF or periodic voltage, with identical polarity or phase, to said plurality of even number of component electrodes to operate said ion trap under the three-dimensional quadrupole ion trap mode.
- 23. (Withdrawn) The on trap of claim 2 wherein said plurality of even number of component electrodes being grouped into a first set composed of odd numbered component electrodes and a second set composed of even numbered component electrodes, said mechanism constructed and arranged to apply a first RF or periodic voltage to the first set electrodes, and a second RF or periodic voltage to the second set electrodes, to operate said ion trap under the two-dimensional linear ion trap mode: the first and second RF or periodic voltages having opposite po arities or phase deference of

180 degree.

- 24. (Withdrawn) The icn trap of claim 65 wherein said machanism being an electrical switching device.
- 25. (Withdrawn) The icn trap of claim 2 wherein said ion trap operates to trap external inlet ions under the two-dimensional linear ion trap mode.
- 26. (Withdrawn) The ich trap of claim 2 wherein said ion trap operates to analyze the trapped ion-mass under the three-dimensional quadrupole ion trap mode.
- 27. (Cancelled)
- 28. (Cancelled)
- 29. (Currently amended) The ion trap of A-method of operating an ion trap in claim 3, wherein for comprising: keeping the amplitude and frequency of the RF voltage or amplitude and period of the periodic voltage of the ion trap being kept at predetermined values; simultaneously sweeping or seanning the amplitude of the DC voltage and the amplitude and frequency of the AC voltage vs. time of the ion trap being simultaneously sweept or seanned to eject ion mass from the ion trap one after another.
- 30. (Currently amended) The ion trap of A method of operating an ion trap in claim 7. wherein for comprising: keeping the amplitude and frequency of the RF voltage or amplitude and period of the periodic voltage of the ion trap being kept at predetermined values; simultaneously sweeping or scanning the amplitude of the DC voltage and the amplitude and frequency of the AC voltage vs. time of the ion trap being simultaneously swept or scanned to eject ion mass from the ion trap one after another.
- 31. (Withdrawn) A method of operating an ion trap in claim 12, said method comprising; keeping amplitude and frequency of the RF voltage or amplitude and period of the periodic voltage at predetermined values; simultaneous y sweeping or scanning the amplitude of the DC voltage and the amplitude and frequency of the AC voltage vs. time to eject ion mass from the on trap one after another.
- 32. (Cancelled)
- 33. (Currently amended) The ion trap of A method of operating an ion trap in claim 3. wherein for comprisings to eping the frequency of the RF voltage or the period of the periodic voltage and the frequency of the AC voltage of the ion trap being kept at predetermined values; sim-thaneously sweeping or scanning the amplitudes of the RF voltage or the periodic voltage, the AC voltage and the DC voltage vs the time of the ion trap being simultaneously swept or scanned to eject ion mass from the trap one after another.
- 34. (Currently amended) The ion trap of A-method of operating an ion trap in claim 7, wherein for comprising: keeping the frequency of the RF voltage or the period of the

periodic voltage and the frequency of the AC voltage of the ion trap being kept at predetermined values; simultaneously sweeping or scanning the amplitudes of the RF voltage or the periodic voltage, the AC voltage and the DC voltage vs the time of the ion trap being simultaneously swept or scanned to eject ion mass from the trap one after another.

- 35. (Withdrawn) A method of operating an ion trap in 12, said method comprising: keeping the frequency of the RF voltage or the period of the periodic voltage and the frequency of the AC voltage at predetermined values: Simultaneously sweeping or scanning the amplitudes of the RF voltage or the periodic voltage, the AC voltage and the DC voltage vs the time to eject ion mass from the trap one after another.
- 36. (Cancelled)
- 37. (Currently amended) The ion trap of A method of operating an ion trap in claim 3, wherein for comprising: keeping setting the frequency of the AC voltage being set to zero; setting the amplitude of the AC voltage being set to be different from the amplitude of the DC voltage or zero; seeping the frequency of the RT voltage or the period of the periodic voltage of the ion trap being kept at predetermined value; Simultaneously sweeping or scanning the amplitudes of the RF voltage and DC voltage vs. time of the ion trap being simultaneously sweeping or scanned to eject ion mass from the trap one after another.
- 38. (Currently amended) The ion trap of A method of operating an ion trap in claim 7, wherein for comprising: keeping setting the frequency of the AC voltage being set to zero; setting the amplitude of the AC voltage being set to be different from the amplitude of the DC voltage or zero; keeping the frequency of the RF voltage or the period of the periodic voltage of the ion trap being kept at predetermined value. Simultaneously sweeping or scanning the amplitudes of the RF voltage and DC voltage vs. time of the ion trap being simultaneously sweepi or scanned to eject ion mass from the trap one after another.
- 39. (Withdrawn) A method of operating an ion trap in claim 12, said method comprising; setting the frequency of the AC voltage to zero; setting the amplitude of the AC voltage to be different from the amplitude of the DC voltage or zero; keeping the frequency of the RF voltage or the period of the periodic voltage at predetermined value. Simultaneously sweeping or scanning the amplitudes of the RF voltage and DC voltage vs. time to eject ion mass. From the trap one after another.
- 40. (Cancelled)
- 41. (Currently amended) The ion trap of claim 3 wherein said DC circuitry controlled to adjusts said electrically variable electrostatic octopole field to compensate distortion of said quadrupole field.
- 42. (Currently amended) The jon trap The method of claim 29 wherein said ion trap is

sealed in a vacuum chamber which is further pumped by a vacuum pump to provide a predetermined level of gas pressure in the trap, <u>said ion trap</u> the method further adjusts the RF voltage, the DC voltage and the AC voltage along with the gas pressure in the trap to eject the ions of the ion rap with maximum or near optimal jumping distance to optimize the mass resolving power.

- 43. (Original) An ion trap system, comprising: an ion trap as in claim 3, sealed within a vacuum chamber being pumped by a vacuum pump to provide gas pressure in the ion trap.
- 44. (Original) An ion trap system, comprising: an ion trap as ir claim 7, sealed within a vacuum chamber being rumped by a vacuum pump to provide gas pressure in the ion trap.
- 45. (Withdrawn) An ich trap system, comprising; an ion trap as in claim 12, sealed within a vacuum chamber being pumped by a vacuum pump to provide gas pressure in the ion trap.
- 46. (Cancelled)
- 47 (Original) The ion trap system of claim 43 wherein said vacuum chamber having vacuum in the range between 10.sup.-2 to 10.sup.-1 mbar.
- 48. (Original) The ion trap system of claim 43 wherein said DC circuitry being constructed and arranged for applying an DC voltage to adjust the intensity of said electrically variable electrostatic octopole field in said ion trap to optimize the mass resolving power when said gas pressure is higher.
- 49. (Currently amended) An ion trap system A-method for providing ions into ion trap system of claim 43, wherein comprising: introducing gas-phase molecules being introduced through a membrane into an ionization area; ionizing said gas-phase molecules being ionized by a radioactive Ni beta source or multi-photon ionization of laser.
- 50. (Original) The ion trap system of claim 44 wherein said vacuum chamber having vacuum in the range betw en 10.sup.-2 to 10.sup.-1 mbar.
- 51. (Original) The ion trap system of claim 44 wherein said DC circuitry being constructed and arranged for applying an DC voltage to adjust the intensity of said electrically variable electrostatic octopole field in said ion trap to optimize the mass resolving power when said gas pressure is higher.
- 52. (Currently amended) An ion trap system A method for previding ions into ion trap system of claim 44. wherein comprising: introducing gas-phase molecules being introduced through a membrane into an ionization area: ionizing said gas-phase molecules being ionized by a radioactive Ni beta source or multi-photon ionization of

laser.

- 53. (Withdrawn) The ich trap system of claim 45 wherein said vacuum chamber having vacuum in the range between 10.sup.-2 to 10.sup.-1 m bar.
- 54. (Withdrawn) The ten trap system of claim 45 whereir said DC circuitry being constructed and arranged for applying an DC voltage to adjust the intensity of said electrically variable electricatic octopole field in said ion trap to optimize the mass resolving power when said gas pressure is higher.
- 55. (Withdrawn) A me hod for providing ions into ion trap system of claim 45. comprising: introducing gas-phase molecules through a membrane into an ionization area; ionizing said gas-phase molecules by a radioactive Ni beta source or multi-photon ionization of laser.
- (Cancelled)
- 57 (Cancelled)
- 58 (Cancelled)
- 59. (Cancelled)
- 60. (Cancelled)
- 61. (Original) A three-dimensional ion trap, comprising: A set of cap electrodes, each of said cap electrodes being further divided into a predetermined number of component electrodes having predetermined shape, a DC circuitry constructed and arranged for applying an DC voltage to a pair of said component electrodes of said cap electrodes to generate an independent electrically variable electrostatic octopole field in said ion trap.
- 62. (Withdrawn) An ion trap, comprising: a ring electrode, the ring electrode being divided, in parallel to its central axis, into a plurality of ever number of component electrodes, said component electrodes being electrically isolated from each other; a mechanism constructed and arranged for switching said ion trap to operate between a three-dimensional quadrupole ion trap mode and a two-dimensional linear ion trap mode.
- 63. (Withdrawn) The on trap of claim 62 wherein said (ing electrode is a cylindrical ring electrode.
- 64. (Currently amended) The ion trap of claim I wherein said ion trap further includes operating means analyzes for ions mass analysis, said means by utilizing the independent, electrically variable electrostatic DC higher multipale filed.

- 65. (Withdrawn) The ion trap of claim 1 wherein said ion trap further includes a mechanism for electrically switch said ion trap to operate between a three-dimensional mode and a two-dimensional mode.
- 66. (Withdrawn) An io i trap of claim 2, said means for electrically switch includes operating said even number of equal parts to switch said ion trap operation between a three-dimensional mode and a two-dimensional mode and wherein said ion trap further includes means for generating a linear RF multipole field when said ion trap operating under the two-dimensional mode.
- 67. (Withdrawn) A two-dimensional ion trap, comprising: a first means for generating a time-varying, two-dimensional substantially quadrupole field, a second means for generating an independent dipole field; a third means for superimposing an independent, two-dimensional electrically variable electrostatic multipole field.
- 68. (Cancelled) An ion trap, comprising: a three-dimensional rotationally symmetric ring electrode and two cap electrodes with surfaces facing toward the inside of the ion trap, each said two cap electrodes being further composed of a first cone electrode and a second disk electrode; a first circuitry for generating a time-varying, substantially quadrupole field, a second circuitry for generating an independent dipole field; a third circuitry for generating an independent, electrically variable electrostatic multipole field.

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